LPM2000 Schedule At-A-Glance

Wednesday, June 14	Thursday, June 15		Friday, June 16
International Conference Room	International Con- ference Room	Omiya Sonic Civic Hall #401	International Confer- ence Room
9:40am-9:50am	9:30am-11:00am	9:30am-10:50am	9:30am-11:00am
Opening Remarks	Session 5:	Session 9:	Session 13:
9:50am-10:50am Session 1:	Fundamental Aspect I.V. Hertel, T. Ooie	Laser Systems and Optical Elements A. Petersen, T. Jitsuno	Micro System P. Herman, S. Nakahara
Overview of Microfabrica-		A. Feiersen, I. Jusuno	
tion A.C. Tam, K. Sugioka			
10:50am-11:10am Coffee Break	11:00am-11:20am Coffee Break	10:50am-11:10am Coffee Break	11:00am-11:20am Coffee Break
11:10am-12:50pm	11:20am-12:30pm	11:10am-12:30pm	11:20am-12:30pm
Session 2:	Session 6:	Session 10:	Session 14:
Ultrafast Pulse Processing	Microfabrication (1)	Surface Microstruc-	Glass Material Processing
(1)	X. Xu, S. Ishizaka	turing	W.T. Sigmon, J. Nishii
M.C. Gower, A. Yabe		H. Endert, Y. Ito	
12:50pm-2:00pm	12:30pm-1:30pm	12:30pm-1:30pm	12:30pm-1:30pm
Lunch	Lunch	Lunch	Lunch
2:00am-3:50pm Session 3: Ultrafast Pulse Processing (2)	1:30pm-3:20pm Session 7: Microfabrication (2) J.J. Dubowski, E. Oh-	1:30pm-3:30pm Session 11: Micro Welding and Cutting	1:30pm-3:40pm Poster Session Omiya Sonic Civic Hall
U. Stamm, H. Misawa	mura	F. Dausinger, T. Ishide	#401
3:50pm-4:10pm	3:20pm-3:40pm	3:30pm-3:50pm	International Confer-
Coffee Break	Coffee Break	Coffee Break	ence Room
4:10pm-5:40pm Session 4: Modification <i>YF. Lu, K. Toyoda</i>	3:40pm-5:40pm Session 8: Industrial Applica- tions V.P. Veiko, K. Washio	3:50pm-5:30pm Session 12: Pulsed Laser Deposition F. Wagner, F. Kokai	3:40pm-5:40pm Session 15: Advanced Applications H. Helvajian, I. Miyamoto
	5:40pm-6:00pm Break	5:30pm-6:00pm Break	5:40pm-5:50pm Closing Remarks
	6:00pm-8:00pm Banquet Omiya Sonic Civic Hall #403 & 404		